

High- Force NEXLINE® Z / Tip / Tilt Platform

NANOMETER PRECISION FOR SEMICONDUCTOR INDUSTRY, WAFER ALIGNMENT



N-510KAWP

- + Self- locking, no heat generation at rest
- + Vacuum compatible and non- magnetic designs feasible
- + Parallel kinematics for enhanced dynamics and better multi- axis accuracy
- + NEXLINE® piezo walking drive free from wear and tear
- + Load capacity to 200 N
- + High precision with integrated 5 nm incremental sensors + picometer resolution dithering mode

Specifications

	Travel ranges	Max. load	Dimensions
N-510 NEXLINE® Z, tip, tilt platform	Z: 1.3 mm θ_x, θ_y : 10 mrad	200 N	Ø 360 mm (14.2") clear aperture: Ø 250 mm

Order Information

N-510KAWP
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Technology

[PiezoWalk® Piezo Stepping Drives | NEXLINE® stepping drives are designed for high push and holding forces of up to 800 N and work with low velocities. Learn more ...](#)

